### Training Request Form

**User Information**

**Name** *

**Email** *

**Registration Status** * I have completed the new user registration and turned in the appropriate forms to the UH Nanofabrication Facility's Administrator.

**Training Request**

**Type** * - Select  
- Facility Orientation  
- Desktop Sputtering System  
- Evaporator  
- Beam Writer  
- Focused Ion Beam (FIB)  
- HF Training  
- Ion Mill  
- Mask Aligner  
- Nanoimprinter  
- Optical Microscopes  
- Profilometer  
- Rapid Thermal Processer  
- Reactive Ion Etcher (RIE 100)  
- Reactive Ion Etcher (RIE 180)  
- Reactive Ion Etcher (RIE 80)  
- Scanning Electron Microscope  
- Spin Coater  
- UHV Sputtering System  
- Vacuum Ovens

**Trainer:** Dr. Long Chang  
**Training Duration:** 0.5 hr

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**Trainer:** Dr. Long Chang  
**Training Duration:** 2 hrs  
**Information:** Please specify the material you wish to evaporate in the comment box below.

**Trainer:** Dr. Long Chang  
**Training Duration:** 2 hrs  
**Information:** Trainees are required to use the equipment within two weeks of training. Please describe your substrate/sample and the patterns you wish to print in the comment box below.